



2822/B

PATENT
005586/D8326 (81784.0208)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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TECHNOLOGY CENTER 2800

In re application of:

Hidenori OGATA et al.

Serial No: 09/291,538

Filed: April 14, 1999

For: LASER ANNEAL METHOD OF A
SEMICONDUCTOR LAYER

Art Unit: 2822

Examiner: M.A. Wilczewski

I hereby certify that this correspondence
is being deposited with the United States
Postal Service with sufficient postage as
first class mail in an envelope addressed
to:

Commissioner for Patents
Washington D.C. 20231, on

December 20, 2002

Date of Deposit

John P. Scherlacher, Reg. No. 23,009

Name

Signature *John P. Scherlacher* Date 12/20/02

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607
(34)

PETITION FOR EXTENSION OF TIME

Non-Fee Amendment
Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

In accordance with 37 C.F.R. 1.136, Applicant respectfully petitions the
Commissioner for a three-month extension of time extending to December 25, 2002,
the period for response to the Office Action dated June 25, 2002. A check for \$920 is
enclosed. The responsive paper(s) are attached.

Please charge any insufficiency or credit any overpayment to Deposit Account
No. 50-1314. A copy of this petition is enclosed.

Respectfully submitted,

HOGAN & HARTSON L.L.P.

Date: December 20, 2002

By: *John P. Scherlacher*

John P. Scherlacher
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